The alpha 2.0 is the ideal spectroscopic ellipsometer for fast, routine thin film measurements. It was designed to provide a perfect balance of accuracy, speed, and price.







Features

Dual-Rotation™ Technology

The alpha 2.0 is equipped with Dual-Rotation ellipsometry technology, featuring a rotating compensator on the source unit and rotating analyzer on the detector unit. This technology provides access to high accuracy and Mueller matrix measurements in a single optical cycle.

CCD Detection System

The alpha 2.0 uses a CCD detector for simultaneous measurement of 190 wavelengths. This allows measurement from 400 nm to 1000 nm in less than a second.

Compact

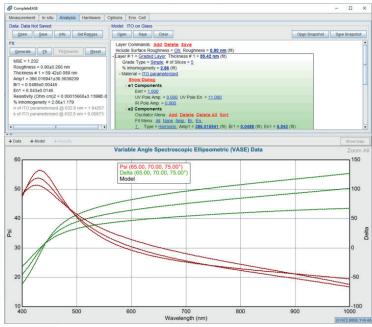
Everything contained in one small package to fit easily on your benchtop. Easy connection to your computer via USB.

Auto Alignment

Alignment is integrated into the data acquisition routine. Automated Z-translation alignment for easy data acquisition. Simply place your sample on the stage and the alpha 2.0 does the rest.

CompleteEASE® Software

CompleteEASE is the world's leading ellipsometry software. Includes prebuilt models for beginners, comprehensive measurement capabilities, and advanced data analysis features.









System specifications

System Configuration (in order)

Light source
Fixed polarizer
Sample
Step scan rotating compensator
Fixed analyzer
Spectrometer and detector

Angles of Incidence

Manual adjustment 65°, 70°, 75° (off sample) 90° (straight through)

Spectral Range

400nm to 1000nm (190 wavelengths)

Light Source

Quartz Tungsten Halogen (QTH)

Data Acquisition Rate

5-10 seconds for full spectrum (typical)

Beam Diameter

Focused, <1 mm

Sample Size

The alpha 2.0 accommodates samples up to 200mm diameter and 16mm thick.

Measurable Quantities

Ellipsometry: Ψ (0°-90°) and Δ (0°-360°) Intensity: % Transmission and % Reflection

Depolarization: % Depolarization

Mueller Matrix: 11 normalized elements of the Mueller Matrix (normalized to m_{11}). Useful for samples that are both anisotropic and depolarizing.

Typical Repeatability

Thirty consecutive measurements of native oxide (nominally 2nm) or thermal oxide (nominally 25nm) on silicon with a warm system at 70° angle and ten second averaging with fixed sample:

δthickness < 0.01nm *1-standard deviation







Facility requirements

Environmental Operating Range

Temperature: 10°C to 35°C

Humidity: 20% to 80% (non-condensing)

Power

100/240 VAC, 47-63Hz, <1 Amp

Ambient Lighting

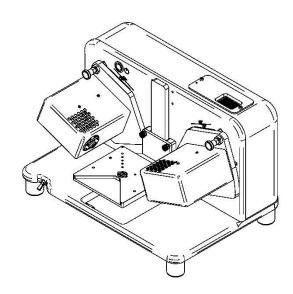
RCE technology allows accurate measurements under normal room light conditions.

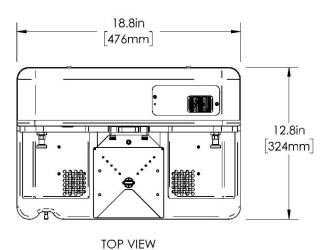
Weight

39 lbs. (excluding computer)

Dimensions

Width 18.8" Depth 12.8" Height 12.3"





12.3in [311mm]

FRONT VIEW



